



US00D803908S

(12) **United States Design Patent** (10) **Patent No.:** **US D803,908 S**
Yamaguchi et al. (45) **Date of Patent:** **** Nov. 28, 2017**

(54) **ROTARY TOOL FOR BOAT OF SEMICONDUCTOR MANUFACTURING APPARATUS**

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(**) Term: **15 Years**

(21) Appl. No.: **29/572,546**

(22) Filed: **Jul. 28, 2016**

(30) **Foreign Application Priority Data**

Feb. 10, 2016 (JP) 2016/002833

(51) **LOC (10) Cl.** **15-09**

(52) **U.S. Cl.**
USPC **D15/130; D15/140; D8/349**

(58) **Field of Classification Search**
USPC D8/8, 14, 36, 61, 89, 130, 142, 337, 349, D8/352, 373, 499; D13/8; D15/4, 5, 9, D15/29, 77, 102, 130, 140, 199, 230, D15/230.12, 230.14, 230.16; D18/10, D18/34.2, 34.8, 40, 46, 58; D24/219, D24/232; D32/1, 3, 5, 7, 13, 14, 19, 21, D32/23, 25, 27, 29, 32, 33, 35
CPC B23Q 5/043; B24D 5/16; H01L 27/1021
See application file for complete search history.

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(57) **CLAIM**

We claim the ornamental design for a rotary tool for boat of semiconductor manufacturing apparatus, as shown (and described).

DESCRIPTION

FIG. 1 is a perspective view of a rotary tool for boat of semiconductor manufacturing apparatus showing my new design;

FIG. 2 is a front elevational view thereof;

FIG. 3 is a rear elevational view thereof;

FIG. 4 is a left side elevational view thereof;

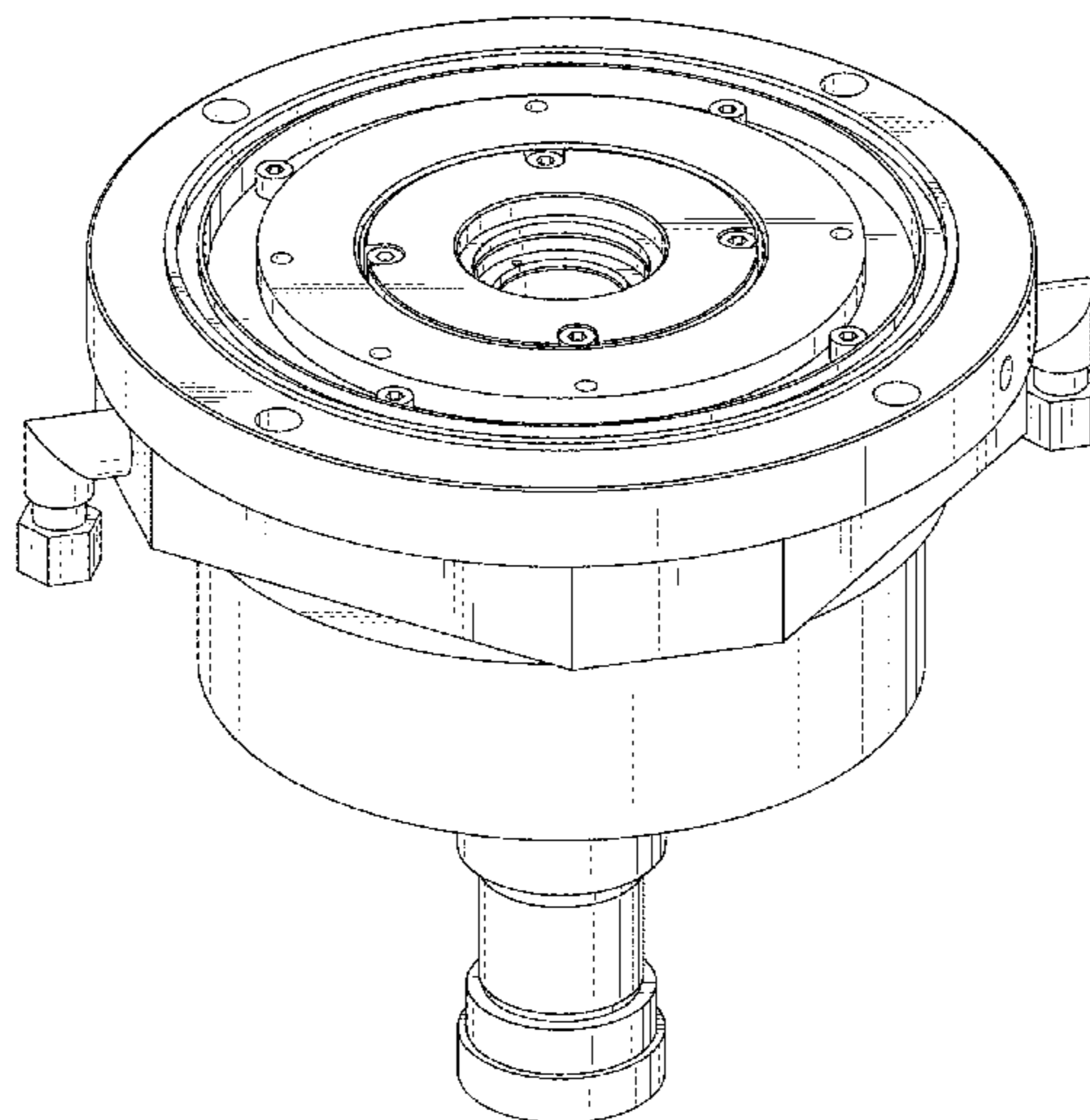
FIG. 5 is a right side elevational view thereof;

FIG. 6 is a top plan view thereof;

FIG. 7 is a bottom plan view thereof; and,

FIG. 8 is a cross-sectional view taken along line 8-8 in FIG. 6 thereof.

1 Claim, 8 Drawing Sheets



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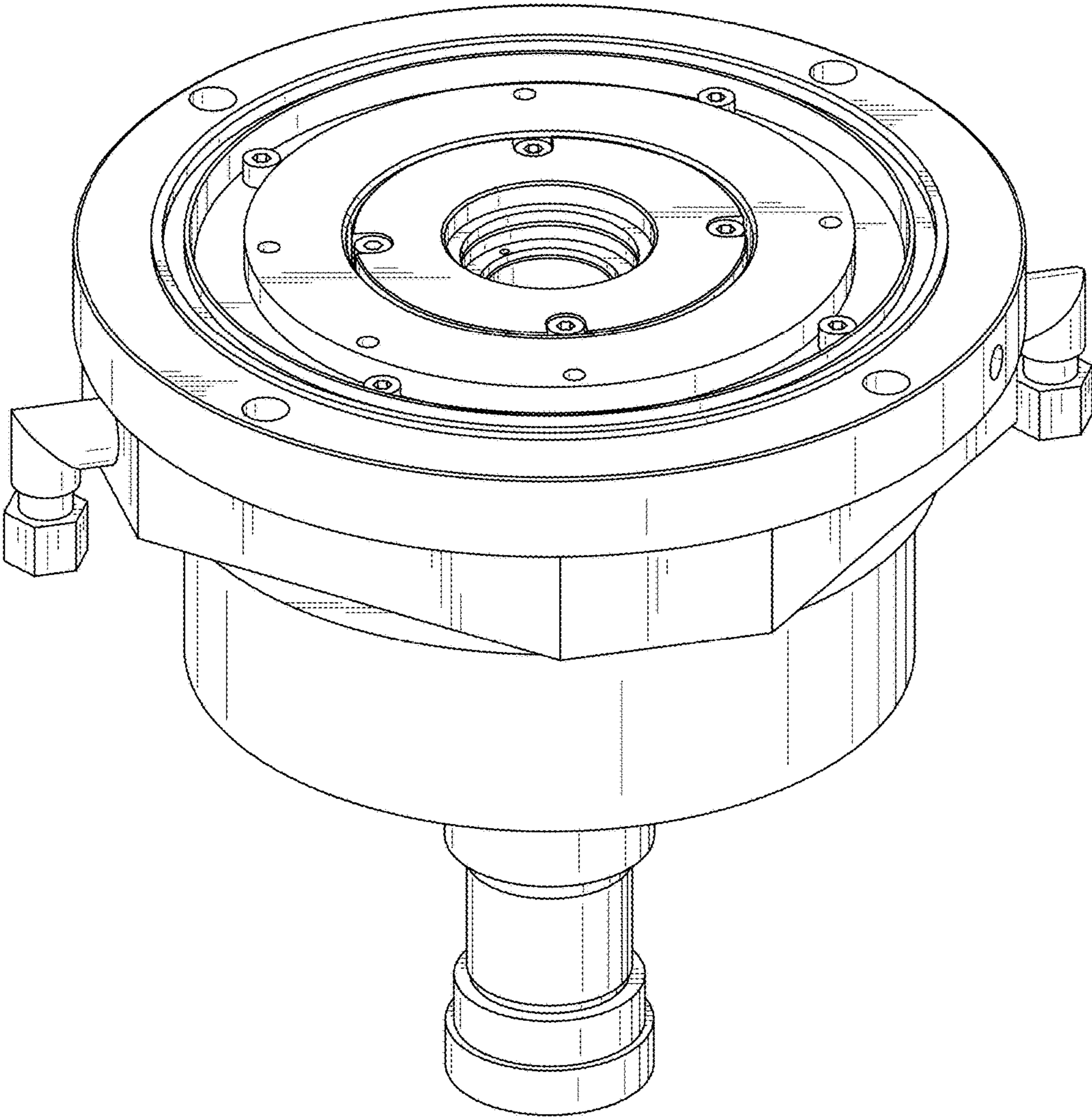


FIG. 1

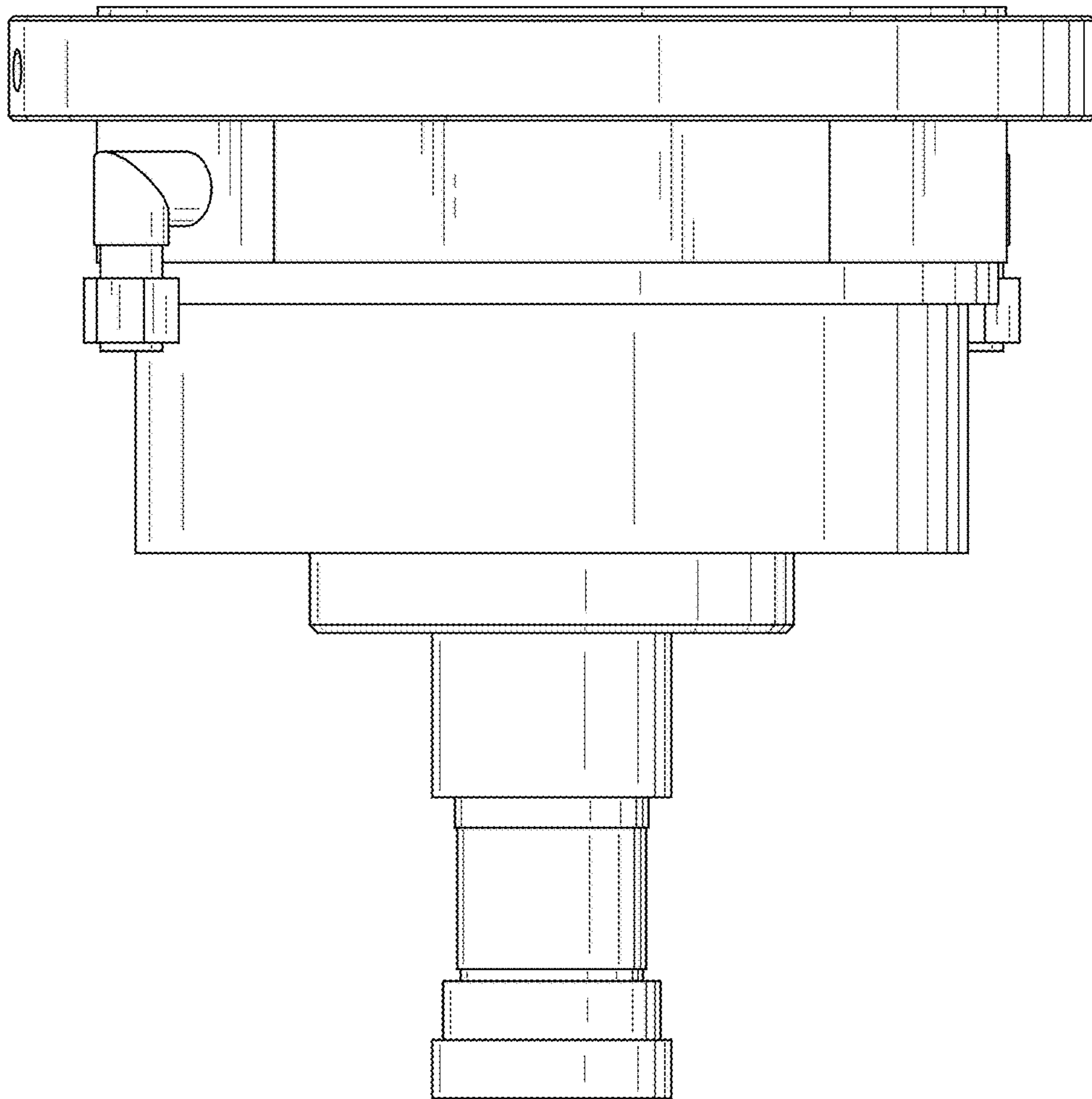


FIG. 2

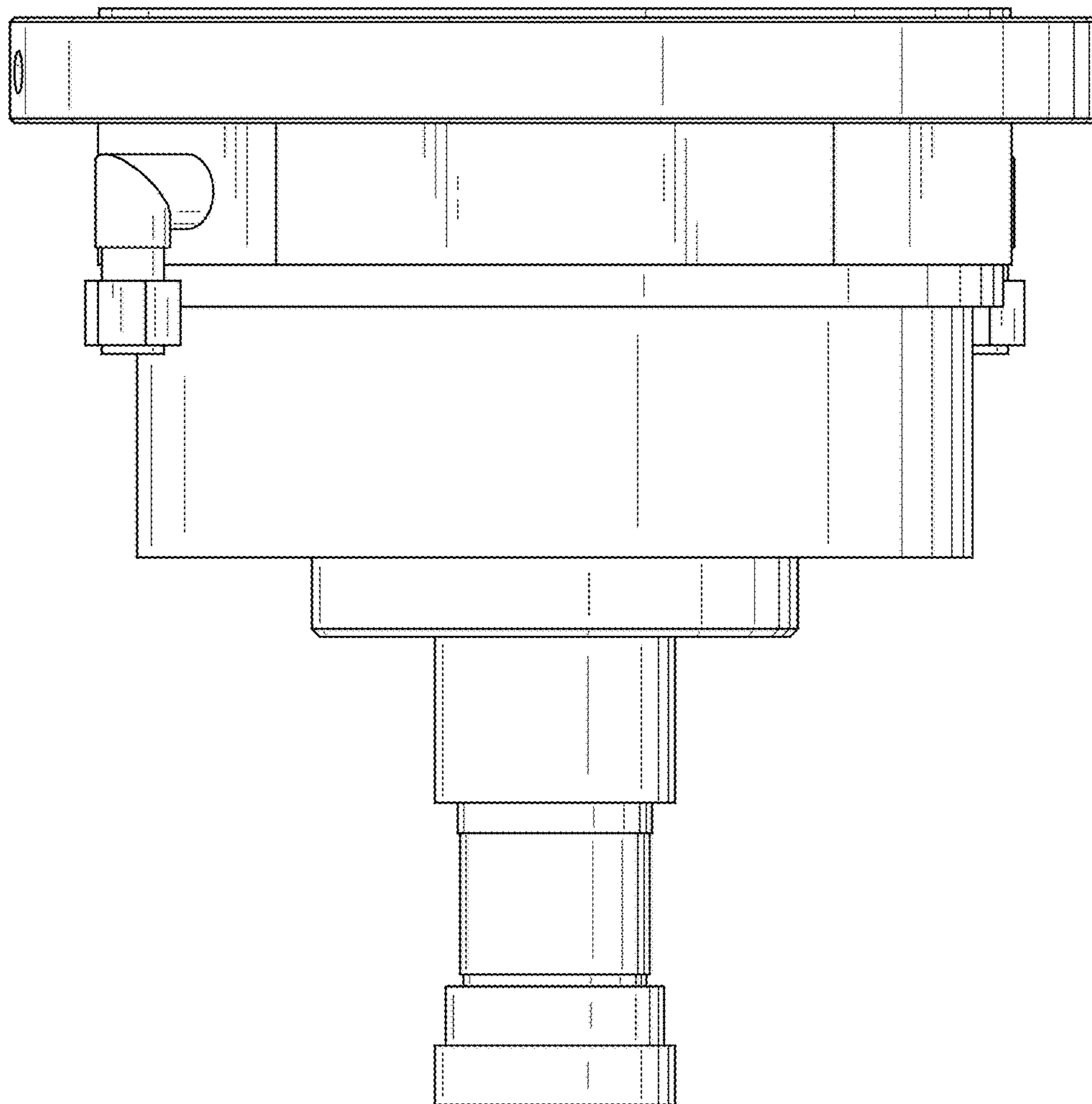


FIG. 3

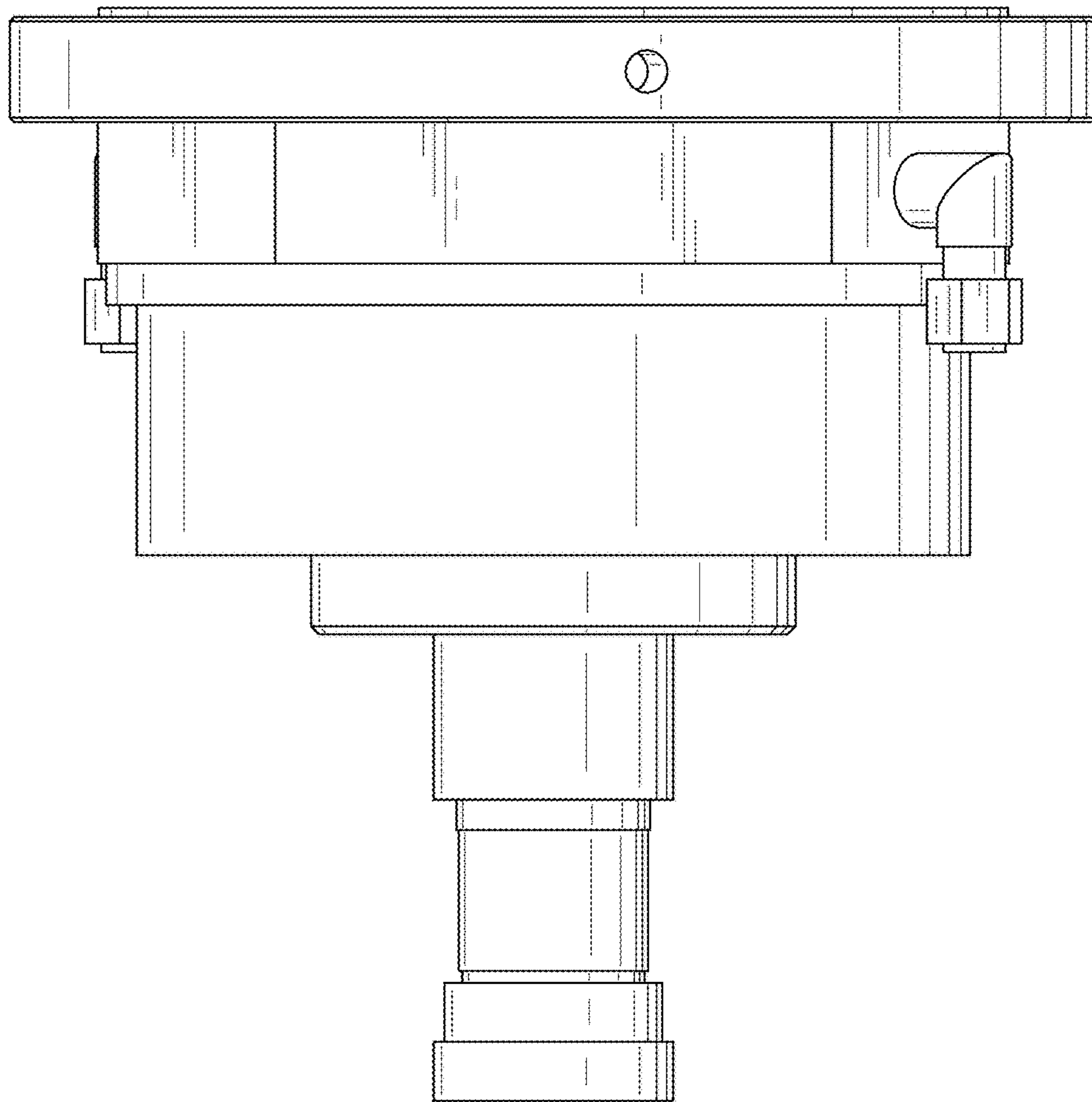


FIG. 4

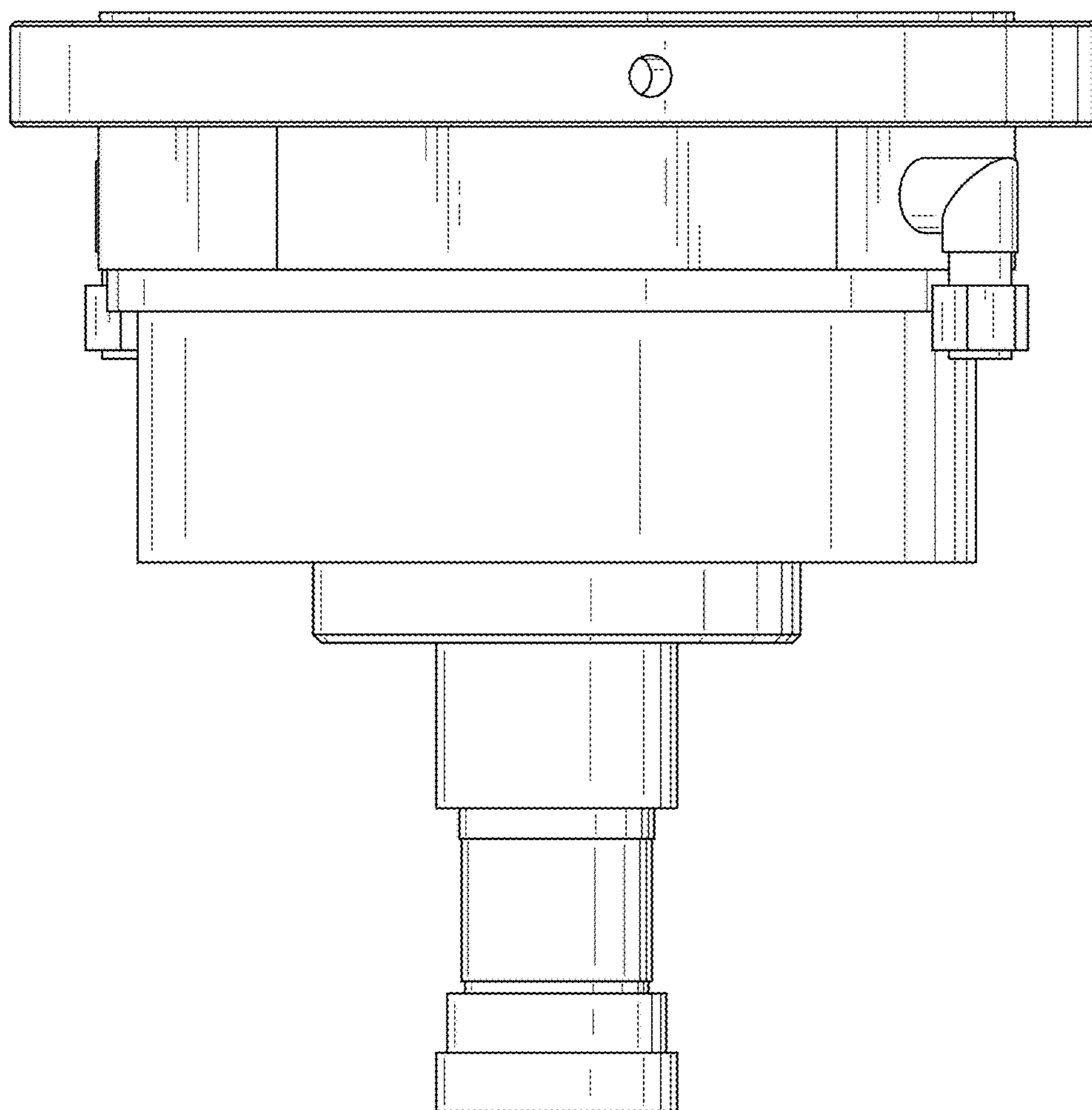


FIG. 5

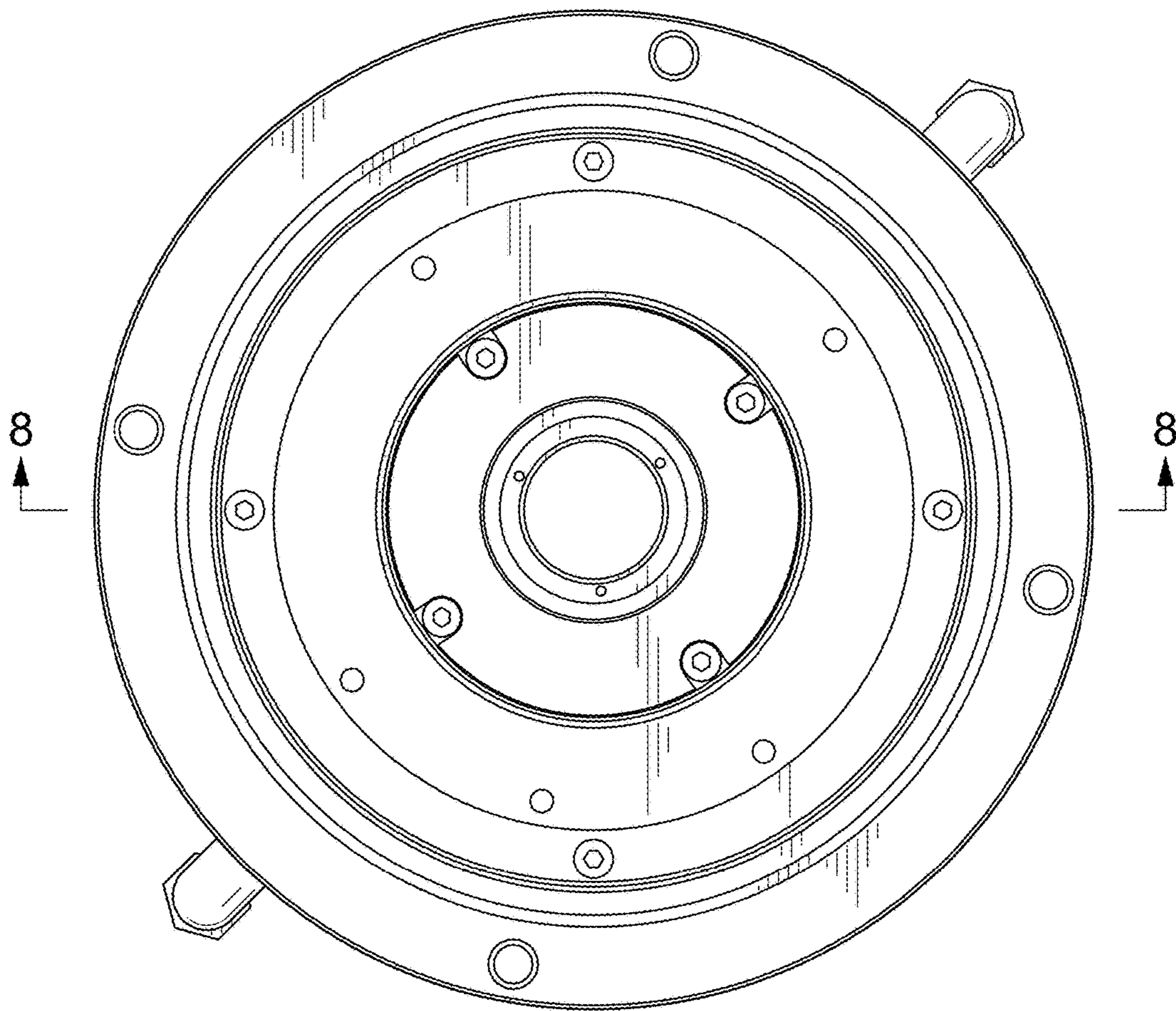


FIG. 6

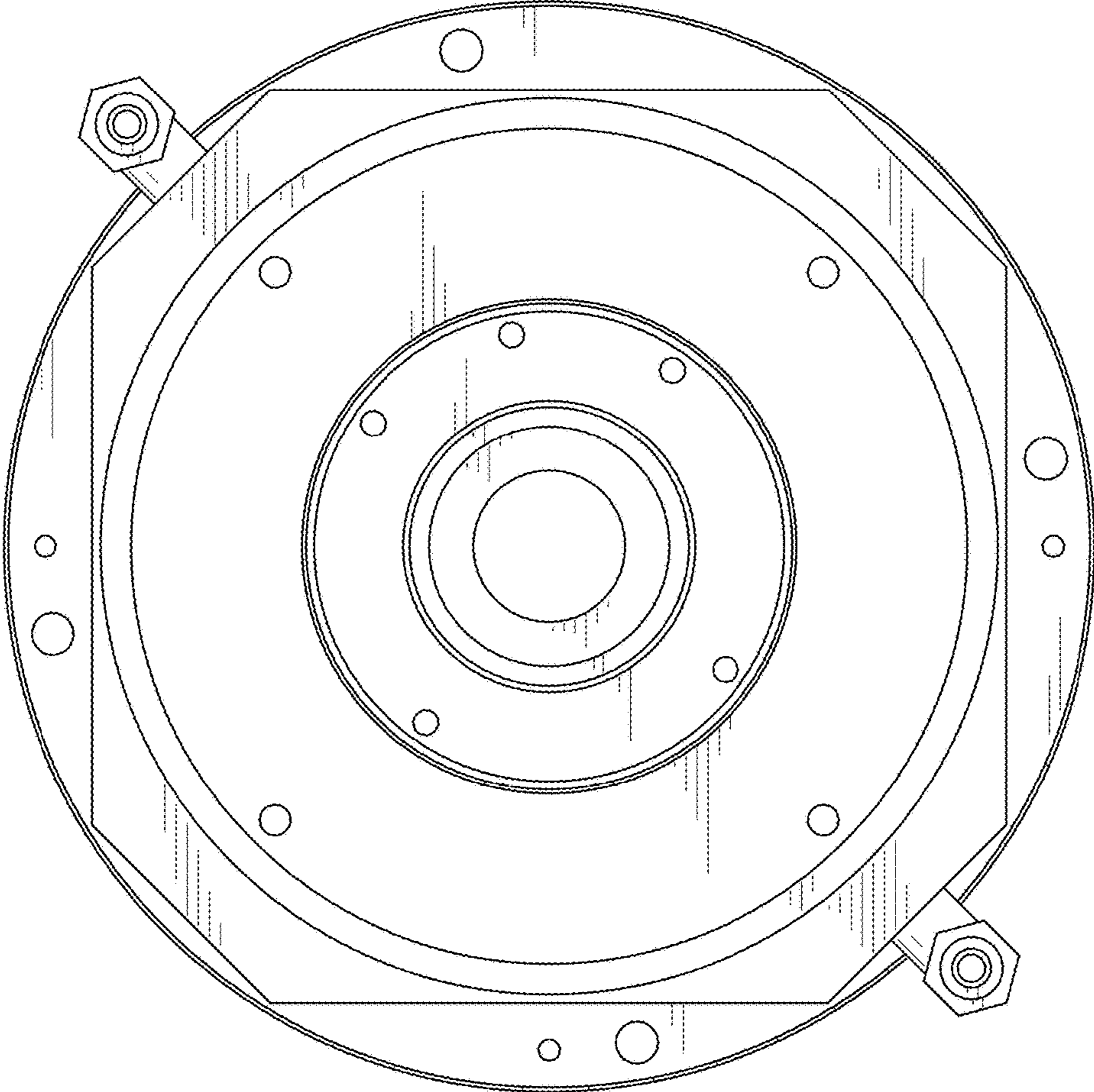


FIG. 7

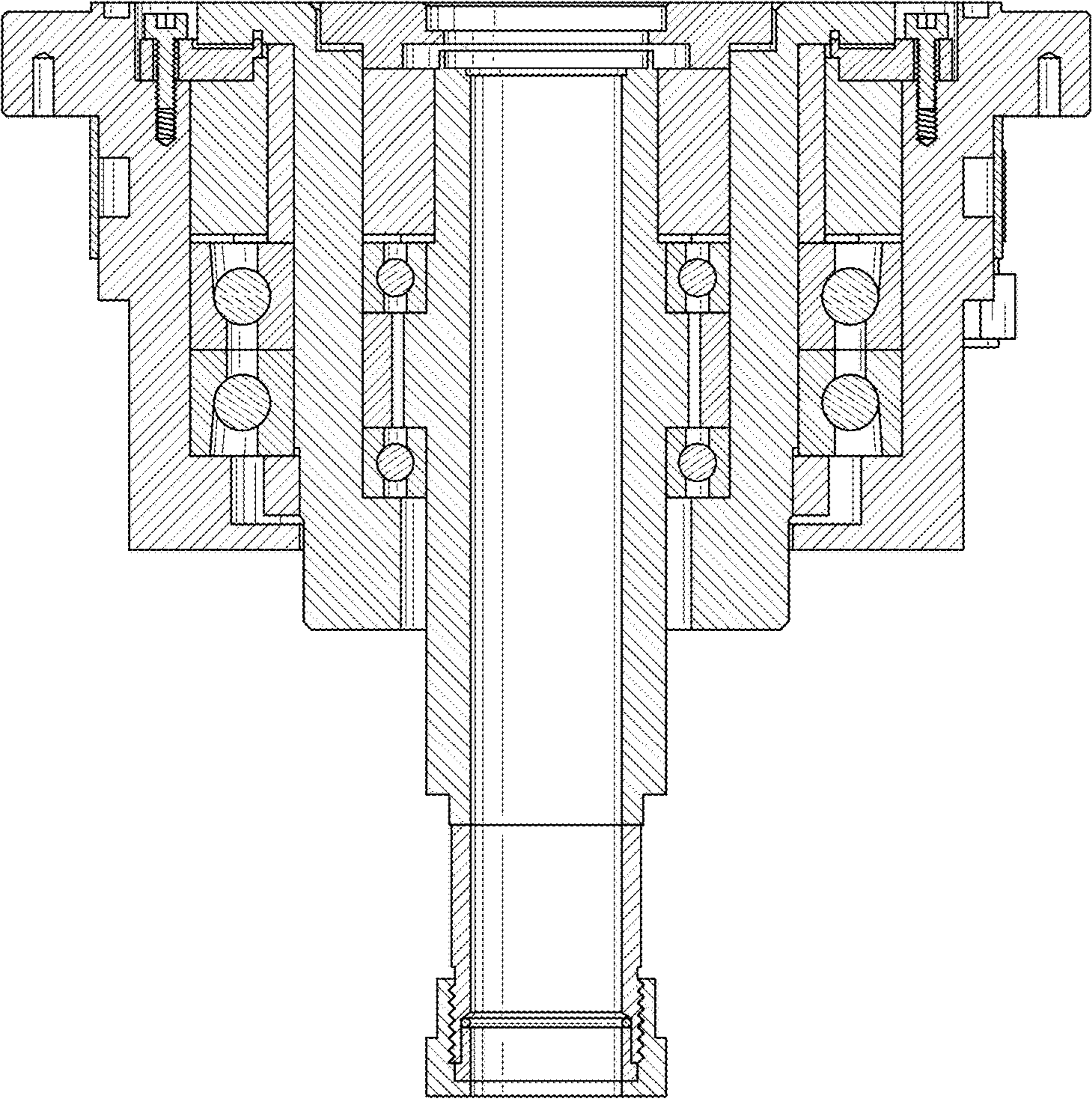


FIG. 8